

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re: Application of: SINGH et al.

Appln No.:

10/082,010

Examiner:

Umez Eronini, Lynette T.

Date Filed:

February 22, 2002

Group:

1765

For:

SLURRY AND METHOD FOR CHEMICAL MECHANICAL POLISHING

OF METAL STRUCTURES INCLUDING REFRACTORY METAL

BASED BARRIER LAYERS

CERTIFICATE UNDER 37 CFR 1.8(a)

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class mail in an envelope addressed to the Mail Stop Amendment, Commissione for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on April 28, 2005.

Neil R. Jetter

Reg. No. 46,803

REPLY TO OFFICE ACTION

Mail Stop Amendment Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated November 29, 2004, a Reply is presented as follows:

A complete Claim listing appears on pages 2-7.

Remarks/Arguments appear on pages 8-12 of this paper.